



PATENT

-1-

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Akshey Seghal

Application No.: 10/620,895

Filed: July 16, 2003

For: COMPOSITIONS AND METHOD  
FOR REMOVING PHOTORESIST  
AND/OR RESIST AT PRESSURES  
RANGING FROM AMBIENT TO  
SUPERCritical

Confirmation No.: 8934

Group No.: 1746

Examiner: Bibi Sharidan Carrillo

**SMALL ENTITY STATEMENT**  
**37 CFR 1.27**

353 Sacramento Street, Suite 2200  
San Francisco, CA 94111  
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M/S RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on May 3, 2005.

STALLMAN & POLLOCK LLP

Dated: 05/3 /2005 By: Georgia K. Stith  
Georgia K. Stith

Sir:

Applicant is a small entity.

Respectfully submitted,

STALLMAN & POLLOCK LLP

Date: May 3, 2005

By: Jason D. Lohr  
Jason D. Lohr  
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Attorneys for Applicant(s)

Atty Docket No.: SCP-9410